



file

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
(Case No. 213.007-US)

In the Application of: YE ET AL.

Serial No: 10/815,573

Filed: APRIL 1, 2004

Title: SYSTEM AND METHOD OF LITHOGRAPHY  
SIMULATION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

) Group Art Unit: 1756

) Before Examiner:

)

)

)

)

I hereby certify that this correspondence is  
being deposited with the United States  
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Patents, P.O. Box 1450, Alexandria, VA  
22313-1450 on January 10, 2005  
Date

Michiko Sites  
(person signing this certificate)

Michiko Sites  
Signature

FIFTH INFORMATION DISCLOSURE STATEMENT

Dear Sir:

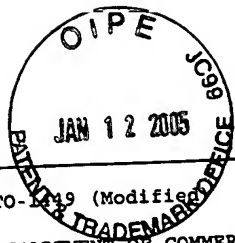
Submitted herewith is one (1) sheet of a modified Form PTO-1449. A copy of each  
document cited on the attached Form PTO-1449 is also submitted.

It is respectfully requested that the Examiner make his/her consideration of these  
references formally of record with the initial Office Action.

Respectfully submitted,

Neil A. Steinberg, Reg. No. 34,735  
Telephone No. 650-968-8079

Date: January 10, 2005



Sheet 1 of 1

PTO-1449 (Modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  INFORMATION DISCLOSURE STATEMENT BY APPLICANT	ATTY. DOCKET NO. <b>213.007-US</b>	SERIAL NUMBER <b>10/815,573</b>
	APPLICANT(S) <b>Ye et al.</b>	
	FILING DATE <b>April 1, 2004</b>	FILING DATE <b>1756</b>

## U.S. PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
	5,563,702	10/1996	Emery et al.			
	5,737,072	4/1998	Emery et al.			

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	"Photomask Production Integration of KLA STARlight™ 3000 System", Kalk et al, Proc. Of SPIE, Vol. 2621, 15 <sup>th</sup> Annual BACUS Symposium on Photomask Technology and Management, December 1995, pp.112-121
	"Defect Detection and Classification in VLSI Pattern Inspection", Soo-Ik Chae, September 1987, Ph.D. Dissertation

EXAMINER	DATE CONSIDERED
EXAMINER: Initial citation if reference was considered. Draw line through citation if not in conformance to MPEP 609 and not considered. Include copy of this form with next communication to applicant.	